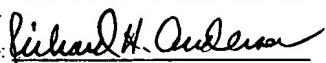


I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail, in an envelope addressed to:  
MS Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA  
22313-1450, on the date shown below.

Dated: October 5, 2005

Signature:   
(Richard H. Anderson)

Docket No.: 28569/38510  
(PATENT)

JFW

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Mingming Fang et al.

Application No.: 10/677,433

Confirmation No.: 9007

Filed: October 2, 2003

Art Unit: 1765

For: CHEMICAL-MECHANICAL POLISHING  
(CMP) SLURRY AND METHOD OF  
PLANARIZING SURFACES

Examiner: P. A. George

### AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION

MS Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

### INTRODUCTORY COMMENTS

In response to the Office Action dated July 5, 2004, please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 3 of this paper.